

ACKNOWLEDGEMENT RECEIPT

Electronic Version 1.1

Stylesheet Version v1.1.1

Title of Invention

HIGH-PRESSURE PROCESSING CHAMBER FOR A SEMICONDUCTOR WAFER

Submission Type : Information Disclosure
Statement

Application Number:

10/680783



EFS ID:

76231

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First Named Applicant: William Jones

Attorney Docket Number:

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File Listing:

Doc. Name	File Name	Size (Bytes)	Date Produced (yyyymmdd)
us-ids	SSI04001-usldst.xml	2399	2005-01-18
us-ids	us-ids.dtd	7763	2005-01-18
us-ids	us-ids.xsl	12026	2005-01-18
package-data	SSI04001-pkda.xml	1704	2005-01-18
package-data	package-data.dtd	27025	2005-01-18
package-data	us-package-data.xsl	19263	2005-01-18
Total files size		70180	

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